

ABSTRACT

A substrate angle alignment device (3) comprises a plurality of holding sections (10A to 10E) which hold a plurality of substrates (100), respectively in such a manner that the plurality of substrates are placed to be oriented horizontally and arranged vertically, a first up-down unit (21A to 21E) including a plurality of first support sections (11A to 11E), and a second up-down unit (22A to 22E) including a plurality of second support sections (12A to 12E). The device (3) repeats a series of angle alignment operations in which the plurality of holding sections (10A to 10E) are rotated together to perform angle alignment of selected one of the plurality of substrates (100), and the first support section (11A to 11E) corresponding to the aligned substrate (100) is moved up to lift up the substrate (100) with the first support section (11A to 11E), while selecting the substrate in succession. The device (3) moves the plurality of second support sections (12A to 12E) up together to lift up the plurality of aligned substrates (100) supported on the plurality of first support sections (11A to 11E), with the plurality of second support sections (12A to 12E), respectively.